

ABSTRACT

1 This invention is an apparatus for imaging metrology, which in particular embodiments
2 may be integrated with a processor station such that a metrology station is apart from but
3 coupled to a process station. The metrology station is provided with a first imaging camera
4 with a first field of view containing the measurement region. Alternate embodiments include a
5 second imaging camera with a second field of view. Preferred embodiments comprise a
6 broadband ultraviolet light source, although other embodiments may have a visible or near
7 infrared light source of broad or narrow optical bandwidth. Embodiments including a broad
8 bandwidth source typically include a spectrograph, or an imaging spectrograph. Particular
9 embodiments may include curved, reflective optics or a measurement region wetted by a
10 liquid. In a typical embodiment, the metrology station and the measurement region are
11 configured to have 4 degrees of freedom of movement relative to each other.